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**\*BIBDATASHEET\*****CONFIRMATION NO. 4998**

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**\*\* CONTINUING DATA \*\*\*\*\***

This application is a 371 of PCT/JP04/00370 01/19/2004

**\*\* FOREIGN APPLICATIONS \*\*\*\*\***

JAPAN 2003-016659 01/24/2003

Foreign Priority claimed	<input type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 4	TOTAL CLAIMS 15	INDEPENDENT CLAIMS 2
35 USC 119 (a-d) conditions met	<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance				

Verified and Acknowledged      Examiner's Signature      Initials

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**TITLE**

METHOD OF CVD FOR FORMING SILICON NITRIDE FILM ON SUBSTRATE

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